Docket No.: P2001,0337

JAN 2 4 2005

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l'hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on the date indicated below.

By: _____

Date: January 19, 2005

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applic. No.

10/713,690

Confirmation No: 2926

Applicant

Rolf Heine et al.

Filed

November 14, 2003

Title

Method for Performing an Alignment Measurement of Two

Patterns in Different Layers on a Semiconductor Wafer

Art Unit

: 2825

Examiner

Belur V. Keshavan

Docket No.

P2001,0337

Customer No.:

24131

<u>INFORMATION DISCLOSURE STATEMENT</u> <u>UNDER 37 C.F.R. 1.97(i)</u>

Hon. Commissioner for Patents

Sir:

In accordance with 37 C.F.R. 1.98 copies of the following patents and/or publications are submitted herewith:

United States Patent No. 5,952,134 (Hwang), dated September 14, 1999;

United States Patent No. 5,958,632 (Sekiguchi), dated September 28, 1999;

United States Patent No. 6,063,529 (Hwang), dated May 16, 2000;

United States Patent No. 6,077,756 (Lin et al.), dated June 20, 2000;

United States Patent No. 6,181,302 B1 (Lynde), dated January 30, 2001.

ORM PTO-1449 (SUBSTITUTE)

U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE

> INFORMATION DISCLOSURE STATEMENT BY APPLICANT (37 CFR 1.98(b))

Attorney	Docket	No.:
P2001,	0337	

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10/713,690

Applicant

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Filing Date

Group Art Unit

November 14, 2003

2825

U.S. PATENT DOCUMENTS

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EXAMINER INITIALS		PATENT NO.	DATE	PATENTEE	CLASS	SUB CLASS	FILING DATE
	Α	5,952,134	09/14/99	Hwang			1
	В	5,958,632	09/28/99	Sekiguchi			
	С	6,063,529	05/16/00	Hwang.			
	D	6,077,756	06/20/00	Lin et al.			
	E	6,181,302 B1	01/30/01	Lynde			
	F						
	G						
	Н						
	1						

FOREIGN PATENT DOCUMENT

	DOCUMENT NO.	DATE	COUNTRY	CLASS	SUB CLASS	TRAI YES	
J							
K							
L							
М							
N							

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

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EXAMINER		DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

As per the Notice in 1273 OG 55 (August 5, 2003) no copies of any abovementioned U.S. patents and U.S. patent application publications are submitted for any application filed after June 30, 2003.

It is believed that the enclosed prior art is less pertinent than the prior art previously submitted and cited by the Examiner. Kindly place the references in the Patent Office file wrapper.

Respectfully submitted

For Applicants

Date: January 19, 2005

RALPH E. LOCHER REG. NO. 41,947

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